

# Gases Japan TC Chapter and Facilities Japan TC Chapter Joint Meeting Meeting Summary and Minutes (Draft)

#### **SEMI Japan Standards Summer 2017 Meetings**

June 23, 2017, 15:00-17:00 SEMI Japan, Tokyo, Japan

TC Chapter Announcements

Gases Japan TC Chapter: SEMI Japan Standards 2017 Winter Meetings Tuesday, December 12, 2017, 13:00-15:00 SEMI Japan, Tokyo, Japan

Facilities Japan TC Chapter: SEMI Japan Standards 2017 Winter Meetings Tuesday, December 12, 2017, 13:00-15:00 SEMI Japan, Tokyo, Japan

#### **Table 1 Meeting Attendees**

Co-Chairs of Gases Japan TC Chapter:

Hiromichi Enami (Hitachi High Technologies), Isao Suzuki (MKS Japan)

**Co-Chairs of Facilities Japan TC Chapter:** 

Hiromichi Enami (Hitachi High Technologies), Isao Suzuki (MKS Japan)

**SEMI Staff:** Mizue Iwamura (SEMI Japan)

Company	Last	First	Company	Last	First
Hitachi High Technologies	Enami	Hiromichi	HORIBA STEC	Isobe	Yasuhiro
Flow Techno Service	Ishihara	Seiji	MKS Japan	Suzuki	Isao
Fujikin	Hirose	Takashi	Tokyo Electron	Mashiro	Supika
Fujikin	Machii	Yoshifumi	Tokyo Electron Tohoku	Okabe	Tsuneyuki
Fujikin	Kitano	Masafumi	Tri Chemical Laboratories	Hiraki	Tadaaki
Hitachi Metals FineTech	Jinbo	Katsuhiro	SEMI Japan	Iwamura	Mizue
HORIBA STEC	Shimizu	Tetsuo			

<sup>\*</sup> alphabetical order by Company name

## **Table 2 Leadership Changes**

# **Gases Japan TC Chapter**

WG/TF/SC/TC Name	Previous Leader	New Leader
5-year-review TF	Yoshifumi Machii (Fujikin)	Masafumi Kitano (Fujikin)

#### **Facilities Japan TC Chapter**

None.



# **Table 3 Committee Structure Changes Gases Japan TC Chapter** None. **Facilities Japan TC Chapter** None. **Table 4 Ballot Results Gases Japan TC Chapter** None. **Facilities Japan TC Chapter** None. Table 5 Activities Approved by the GCS between meetings of the TC Chapter **Gases Japan TC Chapter** None. **Facilities Japan TC Chapter** None. **Table 6 Authorized Activities Gases Japan TC Chapter** None. **Facilities Japan TC Chapter** None. **Table 7 Authorized Ballots Gases Japan TC Chapter** None. **Facilities Japan TC Chapter** None. Table 8 SNARF(s) Granted a One-Year Extension **Gases Japan TC Chapter** None.

**Facilities Japan TC Chapter** 

None.



Table 9 SNARF(s) Abolished Gases Japan TC Chapter

None.

**Facilities Japan TC Chapter** 

None.

# Table 10 Standard(s) to receive Inactive Status

# **Gases Japan TC Chapter**

Standard Designation	Title
SEMI F82-1012	SPECIFICATION FOR DIMENSION OF MASS FLOW CONTROLLER/MASS
22111102 1012	FLOW METER FOR 1.125 INCH TYPE SURFACE MOUNT GAS
	DISTRIBUTION SYSTEMS
SEMI F83-1012	SPECIFICATION FOR DIMENSION OF TWO PORT COMPONENTS (EXCEPT
22111100 1012	MFC/MFM) FOR 1.125 INCH TYPE TWO FASTENER CONFIGURATION
	SURFACE MOUNT GAS DISTRIBUTION SYSTEMS
SEMI F84-1012	SPECIFICATION FOR DIMENSION OF THREE PORT COMPONENTS
2211110112	(EXCEPT MFC/MFM) FOR 1.125 INCH TYPE TWO FASTENER
	CONFIGURATION SURFACE MOUNT GAS DISTRIBUTION SYSTEMS
SEMI F85-1012	SPECIFICATION FOR DIMENSION OF ONE PORT COMPONENTS FOR
521111 05 1012	1.125 INCH TYPE FOUR FASTENER CONFIGURATION SURFACE MOUNT
	GAS DISTRIBUTION SYSTEMS
SEMI F86-1012	SPECIFICATION FOR DIMENSION OF TWO PORT COMPONENTS (EXCEPT
521111001012	MFC/MFM) FOR 1.125 INCH TYPE FOUR FASTENER CONFIGURATION
	SURFACE MOUNT GAS DISTRIBUTION SYSTEMS
SEMI F87-1012	SPECIFICATION FOR DIMENSION OF THREE PORT COMPONENTS
021111071012	(EXCEPT MFC/MFM) FOR 1.125 INCH TYPE FOUR FASTENER
	CONFIGURATION SURFACE MOUNT GAS DISTRIBUTION SYSTEMS
SEMI F88-1012	SPECIFICATION FOR DIMENSION OF STANDARD SIZE MASS FLOW
521111001012	CONTROLLERS AND MASS FLOW METERS FOR 1.5 INCH TYPE SURFACE
	MOUNT GAS DISTRIBUTION SYSTEMS
SEMI F90-1012	SPECIFICATION FOR DIMENSION OF STANDARD SIZE TWO PORT
22111170 1012	COMPONENTS (EXCEPT MFC/MFM) FOR 1.5 INCH TYPE TWO FASTENER
	CONFIGURATION SURFACE MOUNT GAS DISTRIBUTION SYSTEMS
SEMI F91-1012	SPECIFICATION FOR DIMENSION OF COMPACT SIZE TWO PORT
020011711012	COMPONENTS (EXCEPT MFC/MFM) FOR 1.5 INCH TYPE TWO FASTENER
	CONFIGURATION SURFACE MOUNT GAS DISTRIBUTION SYSTEMS
SEMI F92-1012	SPECIFICATION FOR DIMENSION OF COMPACT SIZE THREE PORT
02111172 1012	COMPONENTS FOR 1.5 INCH TYPE TWO FASTENER CONFIGURATION
	SURFACE MOUNT GAS DISTRIBUTION SYSTEMS
SEMI F93-1012	SPECIFICATION FOR DIMENSION OF ONE PORT COMPONENTS FOR 1.5
52111175 1012	INCH TYPE FOUR FASTENER CONFIGURATION SURFACE MOUNT GAS
	DISTRIBUTION SYSTEMS
SEMI F94-1012	SPECIFICATION FOR DIMENSIONS OF TWO PORT COMPONENTS
SEIVII 191 1012	(EXCEPT MFC/MFM) FOR 1.5 INCH TYPE FOUR FASTENER
	CONFIGURATION SURFACE MOUNT GAS DISTRIBUTION SYSTEMS
SEMI F95-1012	SPECIFICATION FOR DIMENSION OF THREE PORT COMPONENTS FOR
DENTIL 75 1012	1.5 INCH TYPE FOUR FASTENER CONFIGURATION SURFACE MOUNT
	GAS DISTRIBUTION SYSTEMS



#### **Facilities Japan TC Chapter**

Standard Designation	Title
DEMIT 1-0012	SPECIFICATION FOR LEAK INTEGURITY OF HIGH-PURITY GAS PIPING SYSTEMS AND COMPONENTS
DLWII I 100-1012	TEST METHOD FOR DETERMINATION OF LEAK INTEGRITY OF GAS DELIVERY SYSTEMS BY HELIUM LEAK DETECTOR

**Table 11 New Action Items** 

**Gases Japan TC Chapter** 

None.

**Facilities Japan TC Chapter** 

None.

#### **Table 12 Previous Meeting Action Items**

#### **Gases Japan TC Chapter**

Item #	Assigned to	Details
Gas161213-1	SEMI Staff	To watch the progress of Doc.5155, New Standard, Guide for Facilities Data
		Package for Semiconductor Equipment Installation by Building Information
		Modeling (BIM) for Semiconductor Capital Equipment TF of NA Closed

#### **Facilities Japan TC Chapter**

None.

#### [Common Part 1]

#### 1 Welcome, Reminders, and Introductions

Hiromichi Enami, committee co-chair, called the meeting to order at 15:00. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

Attachment: 01\_02\_Required\_Elements\_Reg\_20150327\_E+J.pdf

#### 2 Review of Previous Meeting Minutes

The TC Chapter reviewed the minutes of the previous meeting.

**Motion:** To approve the minutes of the previous meeting with an editorial change. **By / 2<sup>nd</sup>:** Seiji Ishihara (Flow Techno Service) / Tetsuo Shimizu (HORIBA STEC)

**Discussion:** None

**Vote:** 11 in favor and 0 opposed. **Motion passed.** 

#### 3 SEMI Staff Report

Mizue Iwamura gave the SEMI staff report. This report included SEMI Global 2017 Calendar of Events, Global Standards Meeting Schedule, SEMICON WEST, 2017 Critical Dates for SEMI Standards Ballots, A&R Ballot Review, SEMI Standards Publication, JRSC Organization Chart, SEMI TSUSHIN Information, Global Staff Assignment and Staff Contact Information.

**Attachment**: 04\_00\_SEMI Staff Report 20170614\_r3.pdf



#### 4 Liaison Reports

4.1 Facilities North America TC Chapter

Mizue Iwamura (SEMI Japan) reported for the Facilities North America TC Chapter as attached.

**Attachment:** 05\_01\_NA F&G Liaison Report April2017.pdf

4.2 Gases North America TC Chapter

Mizue Iwamura (SEMI Japan) reported for the Gases North America TC Chapter as attached.

**Attachment:** 05\_01\_NA F&G Liaison Report April2017.pdf

4.3 Gases Europe TC Chapter Report

None.

4.4 Facilities Korea TC Chapter Report

None.

[Gases Japan TC Chapter Part]

## 5 Subcommittee and Task Force Reports

5.1 Gas Panel and Metal Seal Test Methods Task Force

None.

5.2 5-year-review Task Force

See Old Business.

5.3 Live Gas Flow Rate Task Force

Tetsuo Shimizu (HORIBA STEC) reported for the Live Gas Flow Rate Task Force. The Task Force met earlier in the day. Of note:

 Round robin test has done by several companies at National Institute of Advanced Industrial Science and Technology (AIST), and Tetsuo Shimizu (HORIBA STEC) reviewed the summary of the last test results.

#### 6 Old Business

6.1 5 Year Review Check

Yoshifumi Machii (Fujikin) addressed the committee on this topic.

**Motion:** To approve 13 SEMI Standards to get "inactive" status. 13 SEMI Standards are as follows;

SEMI F82-1012, SEMI F83-1012, SEMI F84-1012, SEMI F85-1012, SEMI F86-1012, SEMI F87-1012, SEMI F88-1012, SEMI F90-1012, SEMI F91-1012, SEMI F92-1012, SEMI F93-

1012, SEMI F94-1012, SEMI F95-1012.

By / 2<sup>nd</sup>: Yoshifumi Machii (Fujikin) / Seiji Ishihara (Flow Techno Service)

**Discussion:** There is few possibility to revise those SEMI standards.

**Vote:** 10 in favor and 0 opposed. **Motion passed.** 



#### 7 New Business

Yoshifumi Machii (Fujikin) addressed the committee on this topic.

**Motion:** To approve Yoshifumi Machii (Fujikin) to step down from 5-year-review TF, and to approve

Masafumi Kitano (Fujikin) to be a leader of 5-year-review TF.

By / 2<sup>nd</sup>: Yoshifumi Machii (Fujikin) / Isao Suzuki (MKS Japan)

**Discussion:** None.

**Vote:** 10 in favor and 0 opposed. **Motion passed.** 

#### [Facilities Japan TC Chapter Part]

#### 8 Subcommittee and Task Force Reports

8.1 F1 Revision Task Force

The committee discussed to discharge F1 Revision Task Force in next committee. The committee will ask Shuji Moriya (Tokyo Electron Yamanashi) to continue F1 Revision Task Force or not, because Yoshifumi Machii (Fujikin) will step down from the leader of F1 Revision Task Force as well. Thus, there are no activities recently.

#### 9 Old Business

9.1 5 Year Review Check

Yoshifumi Machii (Fujikin) addressed the committee on this topic.

Motion: To approve 2 SEMI Standards to get "inactive" status. 2 SEMI Standards are as follows; SEMI

F1-0812, SEMI F106-1012.

By / 2<sup>nd</sup>: Yoshifumi Machii (Fujikin) / Seiji Ishihara (Flow Techno Service)

**Discussion:** There is few possibility to revise those SEMI standards.

**Vote:** 10 in favor and 0 opposed. **Motion passed.** 

#### 10 New Business

None.

#### [Common Part 2]

#### 11 Next Meeting and Adjournment

The next meeting of the Gases Japan TC Chapter is scheduled for Tuesday, December 12, 2017, 13:00-15:00, SEMI Japan, Tokyo, Japan.

The next meeting of the Facilities Japan TC Chapter is scheduled for Tuesday, December 12, 2017, 13:00-15:00, SEMI Japan, Tokyo, Japan.

See http://www.semi.org/en/events for the current list of meeting schedules.

Having no further business, a motion was made to adjourn. Adjournment was at 17:00.



Respectfully submitted by:

Mizue Iwamura Coordinator, Standards

SEMI Japan

Phone: +81.3.3222.5760 Email: miwamura@semi.org

# Minutes approved by:

Hiromichi Enami (Hitachi High Technologies), Co-chairs	October 24, 2017
Isao Suzuki (MKS Japan), Co-chairs	October 24, 2017

# Table 13 Index of Available Attachments#1

Title	Title
01_02_Required_Elements_Reg_20150327_E+J.pdf	04_00_SEMI Staff Report 20170614_r3.pdf
05_01_NA F&G Liaison Report April2017.pdf	

<sup>#1</sup> Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.